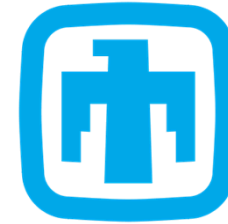




**Massachusetts
Institute of
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Sandia
SAND2015-4385C
**National
Laboratories**

Trapping Characteristics and Parametric Shifts in Lateral GaN HEMTs with SiO₂/AlGaN Gate Stacks

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Purpose

- **AlGaN/GaN HEMTs are desirable for RF/power device applications**
- **Temperature and stress dependent parametric shifts remain a critical reliability issue for HEMT power devices**
- **Explore the properties of slow-detrapping processes in HEMTs and MOS-HEMTs using modified current-transient analysis method**

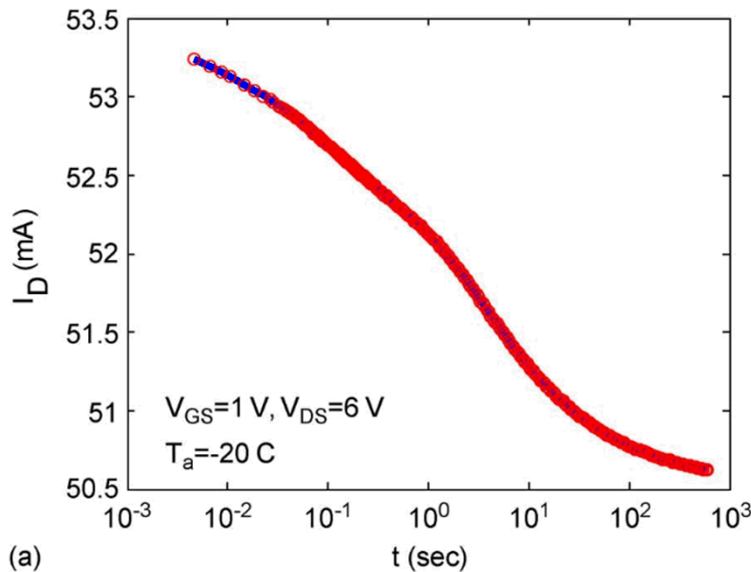
Outline

- **Introduction**
- **Device Schematics**
- **Analytical Techniques**
- **Validation of Analytical Techniques**
- **Off-State Stress Schottky-Gated HEMTs**
 - Off-State Stress-Time Dependent Parametric Shifts
 - Temperature Dependent Off-State Parametric Shifts
- **Off-State Stress MOS-HEMTs**
 - Off-State Stress-Time Dependent Parametric Shifts
 - Temperature Dependent Off-State Parametric Shifts
- **Discussion**
 - Mechanisms of off-state stress parametric shifts
 - Device recovery response
- **Conclusions**

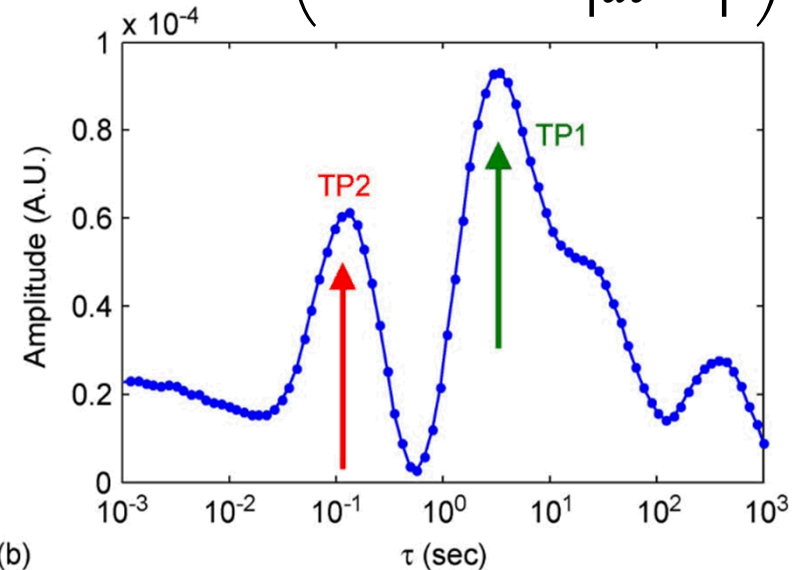
Introduction

$$\Delta I_d = \sum \alpha_i (1 - e^{-t/\tau_i})$$

$$y_{fit} = \min \left(|y - A\alpha|^2 + \left| \frac{d}{dt} A\alpha \right|^2 \right)$$

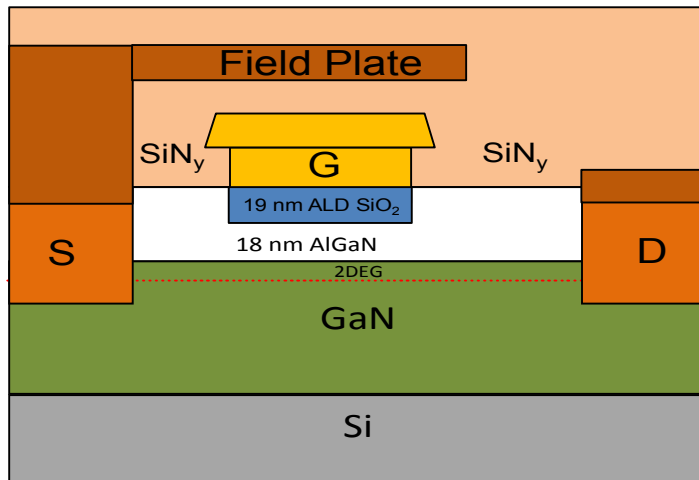
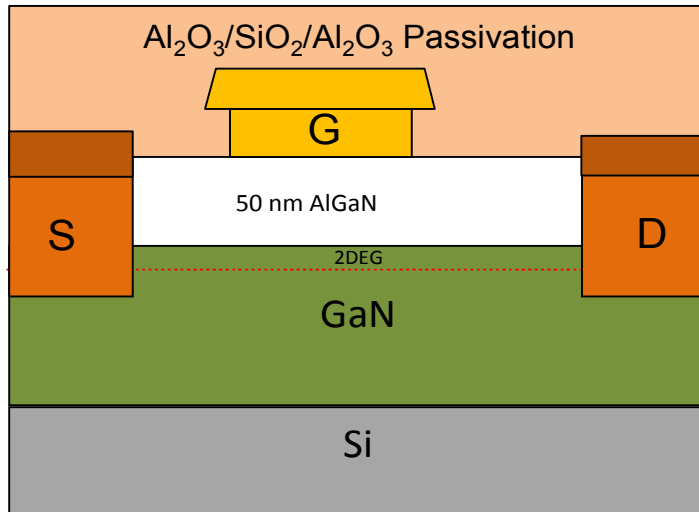


- **Stress-induced parametric shifts remain critical reliability concern for HEMTs**
- **Original current-transient method provided framework for evaluation of slow-detrapping transients**



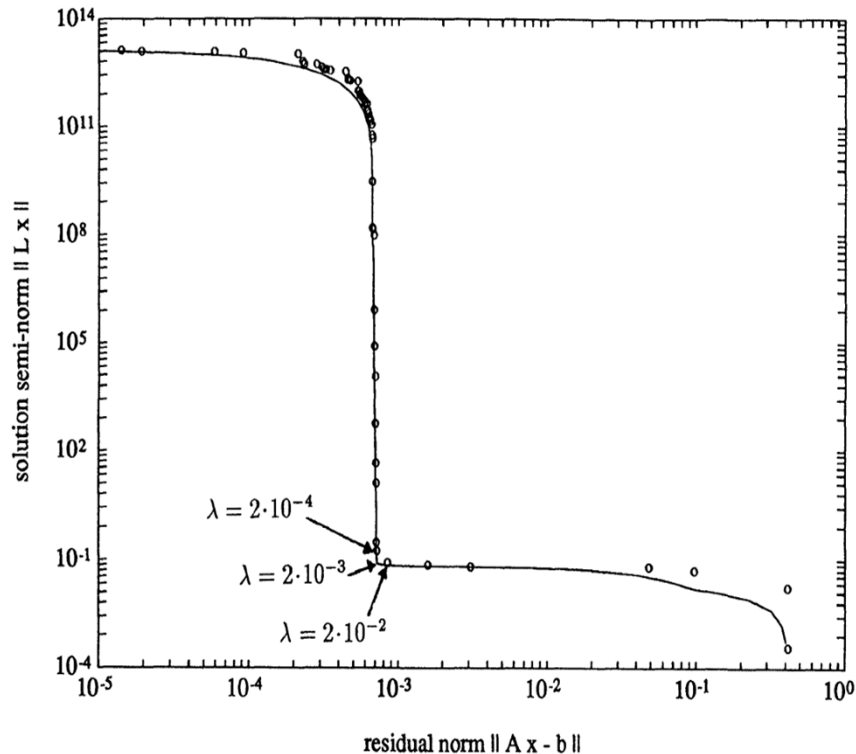
- **Large changes in I_d and V_{th} observed following both *on*- and *off*-state stress**
- **Reconstruction of emission spectrum provides insight into location and trap energy for detrapping processes**

Device Schematics



- Two devices types investigated
 - “Schottky”-gated HEMT
 - MOS-HEMT
- Study the off-state stress / on-state recovery response

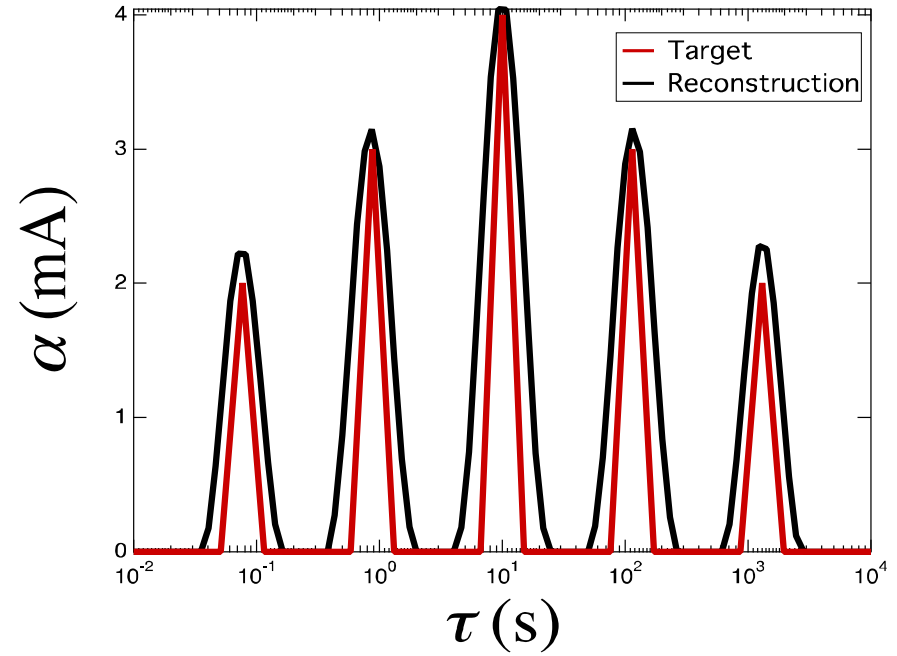
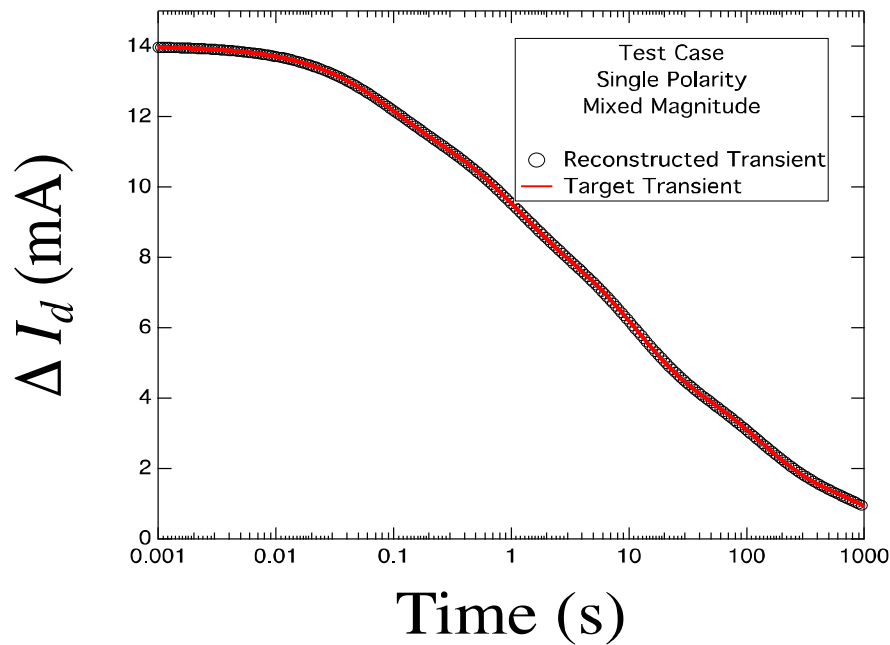
Regularization Analytical Techniques



$$y_{fit} = \min \left(|y - A\alpha|^2 + \lambda \left| \frac{d^2}{dt^2} A\alpha \right|^2 \right)$$

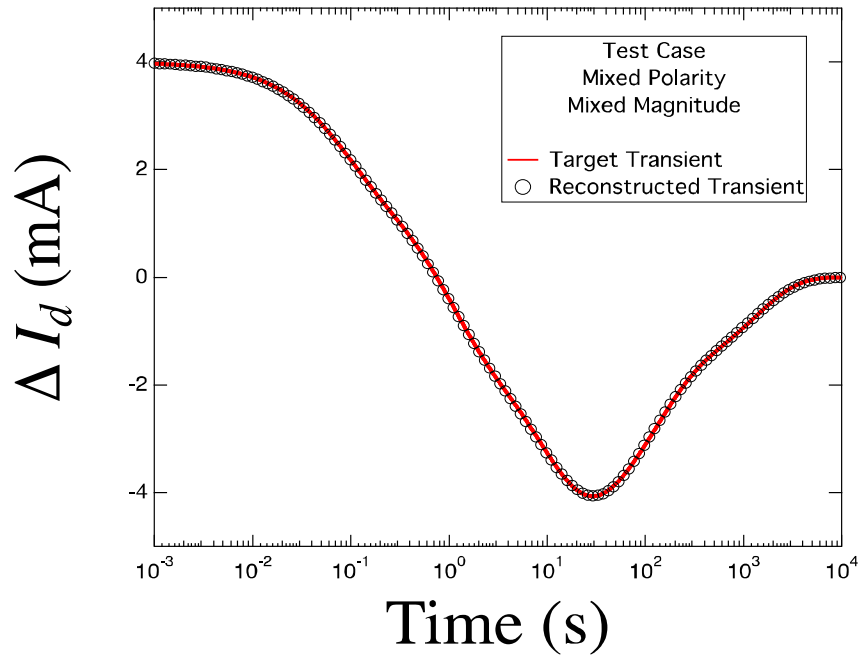
- Tikhonov regularization techniques
- Regularizer enforces parsimony, prior knowledge, curvature on solution
- Optimal choice of λ located on “L”-corner of LSQ term and regularizer
- Used in fields of nuclear physics, chemistry, NMR, L-DLTS, biology, and astronomy

Validation of Analytical Techniques

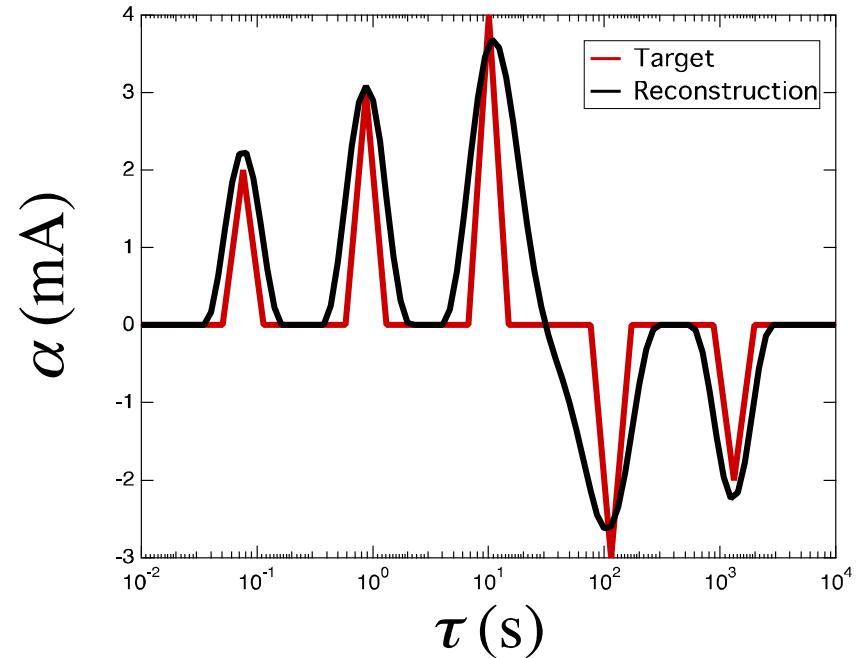


- Artificial time-domain signal representing multiple electron trapping processes
- Modified current-transient method reconstructs the device response
- Time-constant spectrum shows method reconstructs multiple exponential processes with accurate temporal resolution and magnitude

Validation of Analytical Techniques

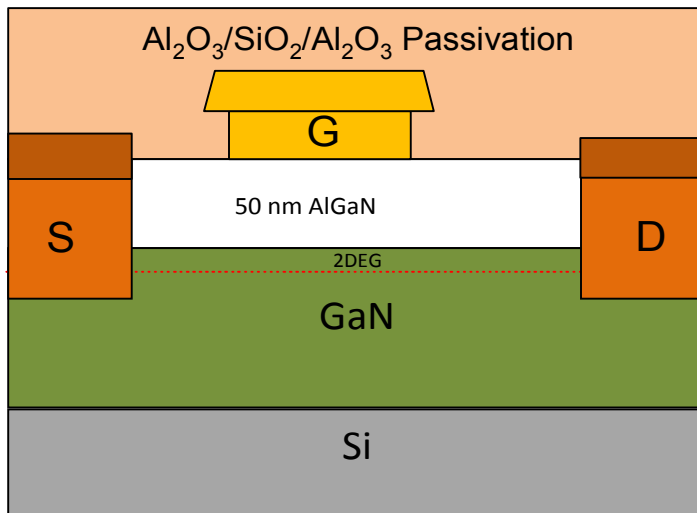


- **Artificial transient representative of simultaneous trapping and emission of electrons**



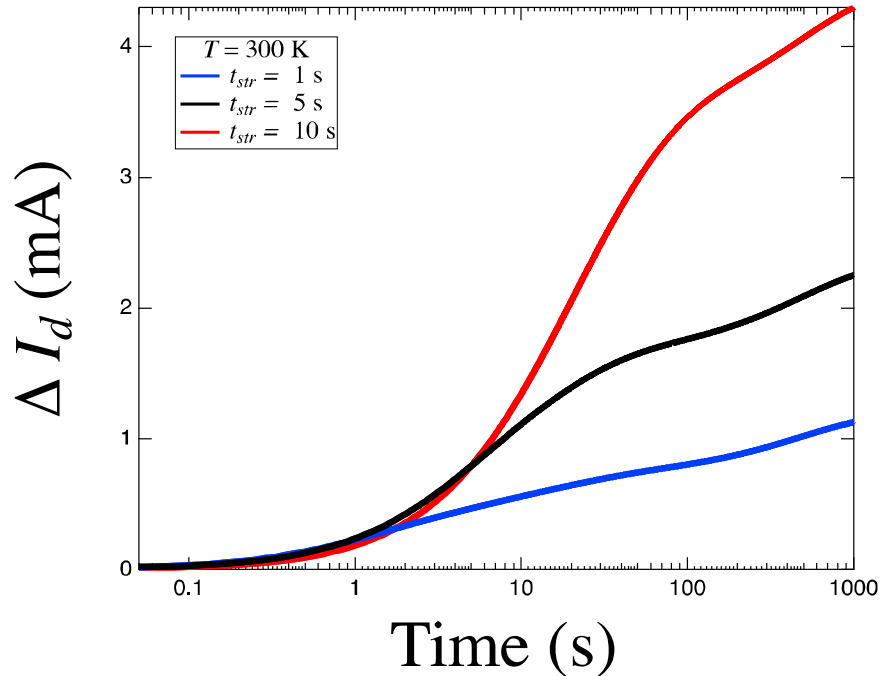
- **Corresponding time-constant spectrum shows both trapping and emission processes are recoverable with accuracy**

Off-State Stress Schottky-Gated HEMTs

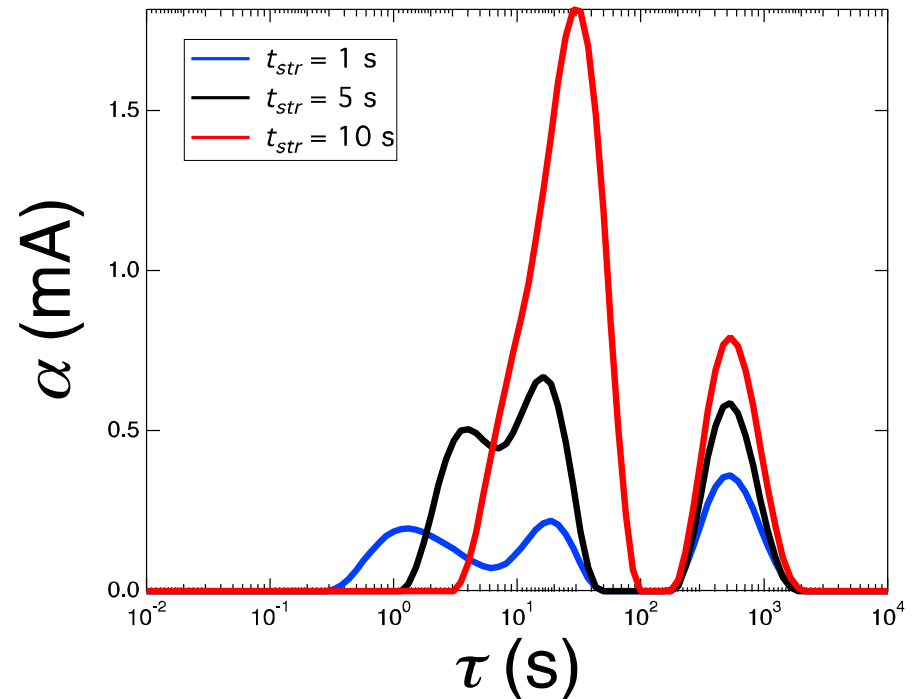


- Stress-time and temperature dependent off-state parametric shifts in I_d
- Off-state stress conditions
$$V_{gs} = -5 \text{ V}$$
$$V_{ds} = 100 \text{ V}$$
- Recovery-state
$$V_{gs} = 1 \text{ V}$$
$$V_{ds} = 0.1 \text{ V}$$

Off-State Stress-Time Dependent Parametric Shifts

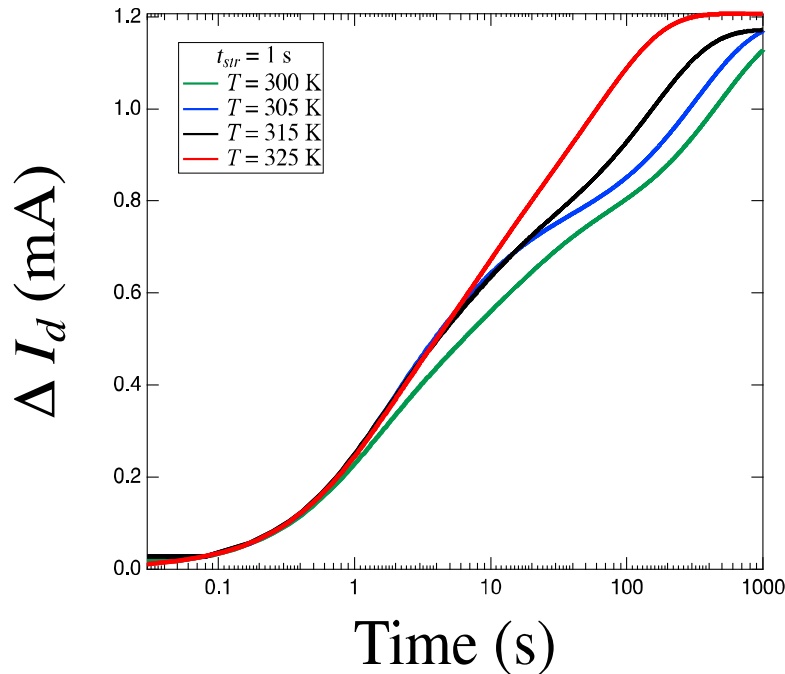


- Large ΔI_d (> 1 mA @ $T = 300$ K) observed following off-state stress
- ΔI_d increases for longer stress time

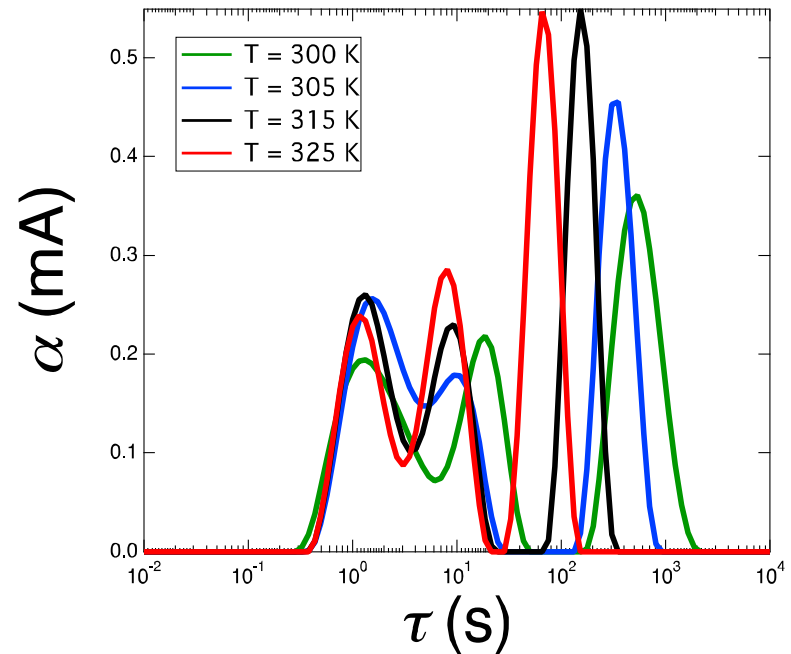


- Spectrum reveals two processes
- Broad stress-time dependent process
- Slower stress-time independent process

Temperature Dependent Off-State Parametric Shifts

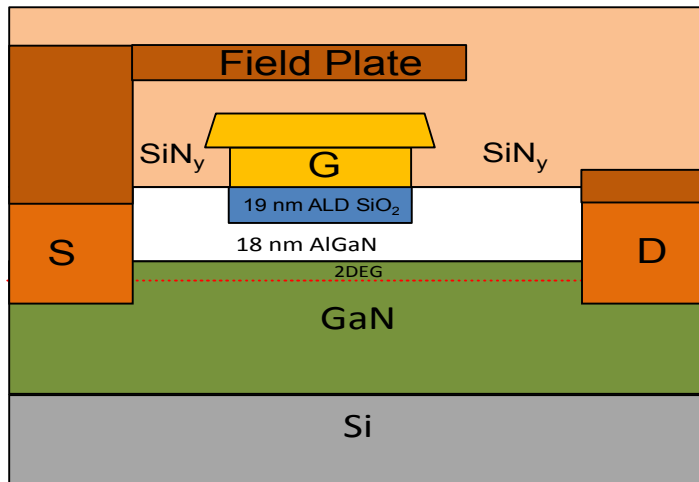


- Large ΔI_d (> 1 mA @ $T = 300$ K) observed following off-state stress
- ΔI_d increases for increasing temperature
- Recovery of I_d increases at longer times for higher temperature



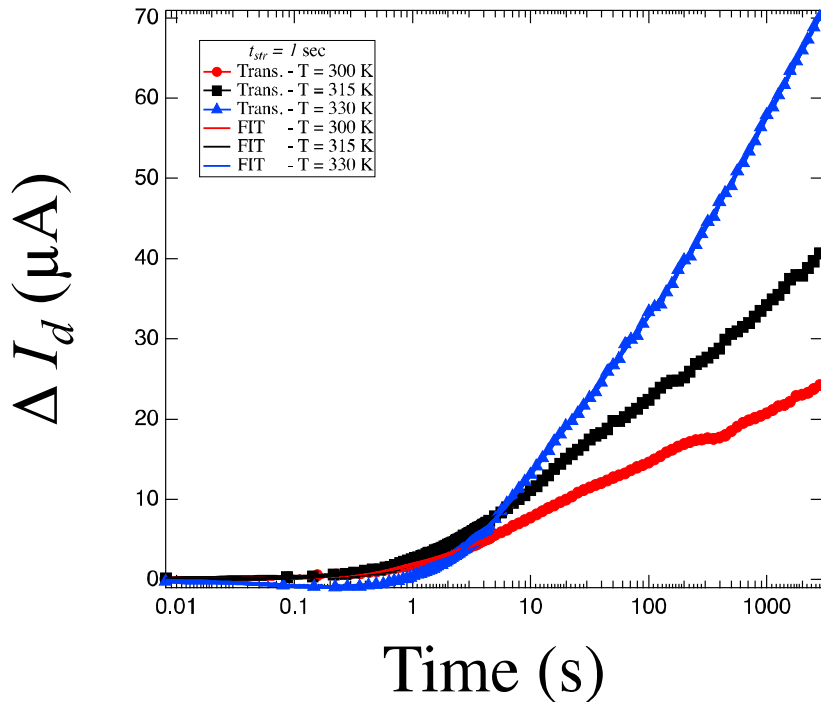
- Spectrum reveals two processes
- Broad stress-time dependent process shows no temperature dependence between 300 K and 325 K
- Slower process exhibits temp. dependence with $E_a = 0.57$ eV

Off-State Stress MOS-HEMT Devices

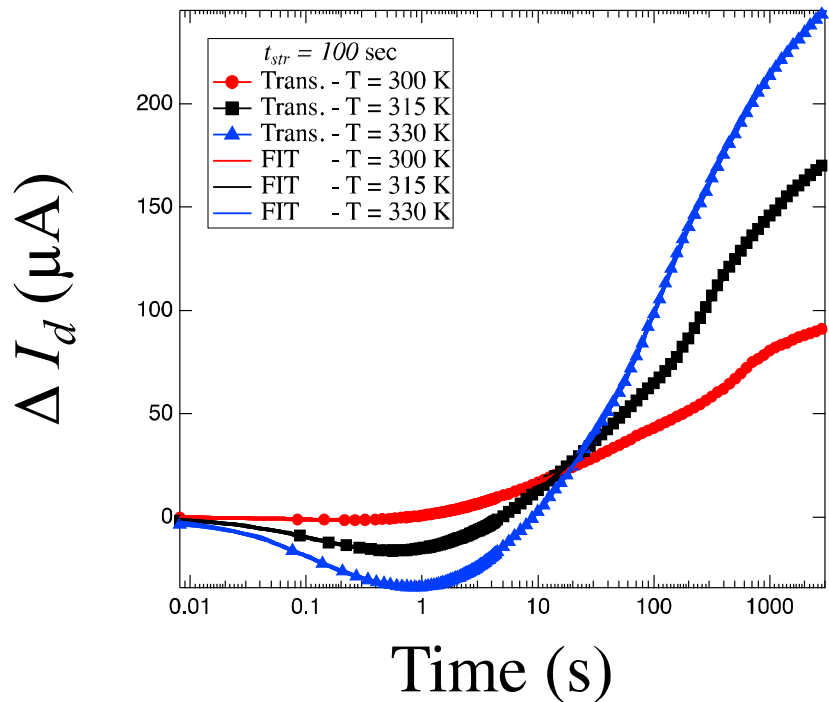


- Stress-time and temperature dependent off-state parametric shifts in I_d
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$$V_{gs} = -5 \text{ V}$$
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$$V_{gs} = 1 \text{ V}$$
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Off-State Stress-Time Dependent Parametric Shifts

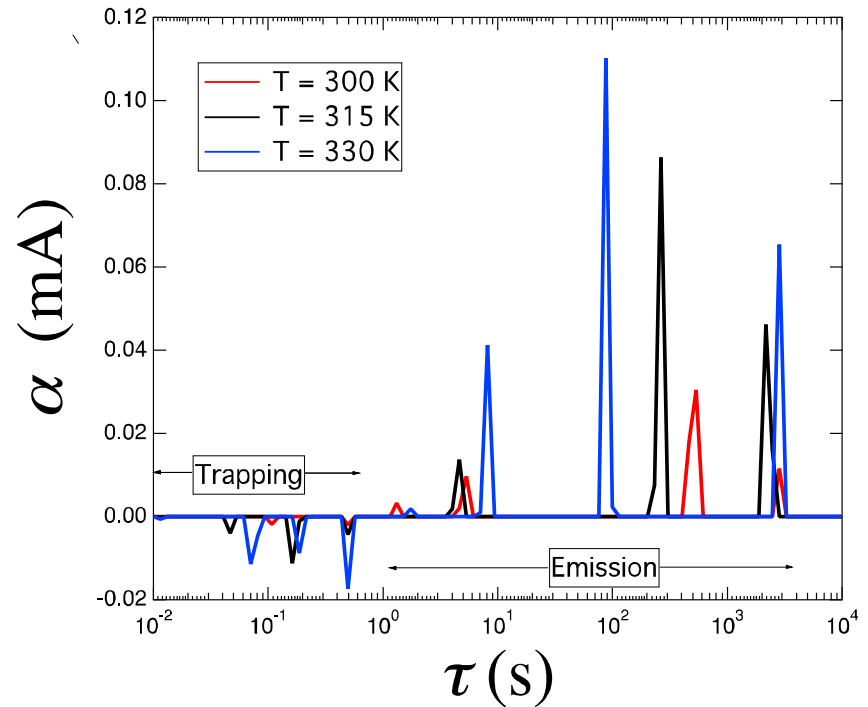
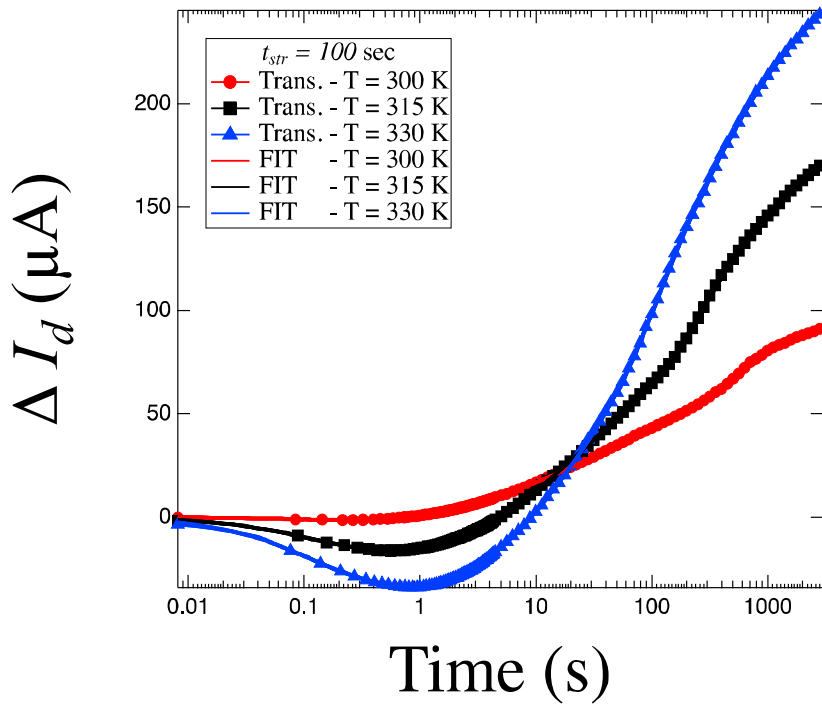


- ΔI_d following off-state stress observed to be much smaller in MOS-HEMT devices
- Increasing temp. leads to larger ΔI_d
- Recovery transient at T = 330 K shows initial decrease followed by positive recovery



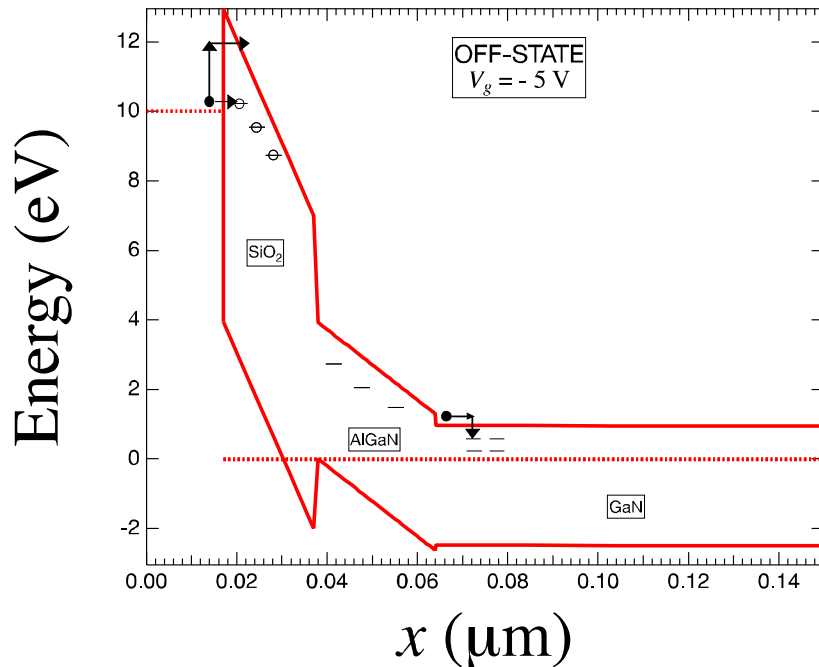
- For longer t_{str} we observe larger ΔI_d
- Short recovery times (< 10 s) exhibit decreasing I_d for increasing temperature

Temperature Dependent Off-State Parametric Shifts



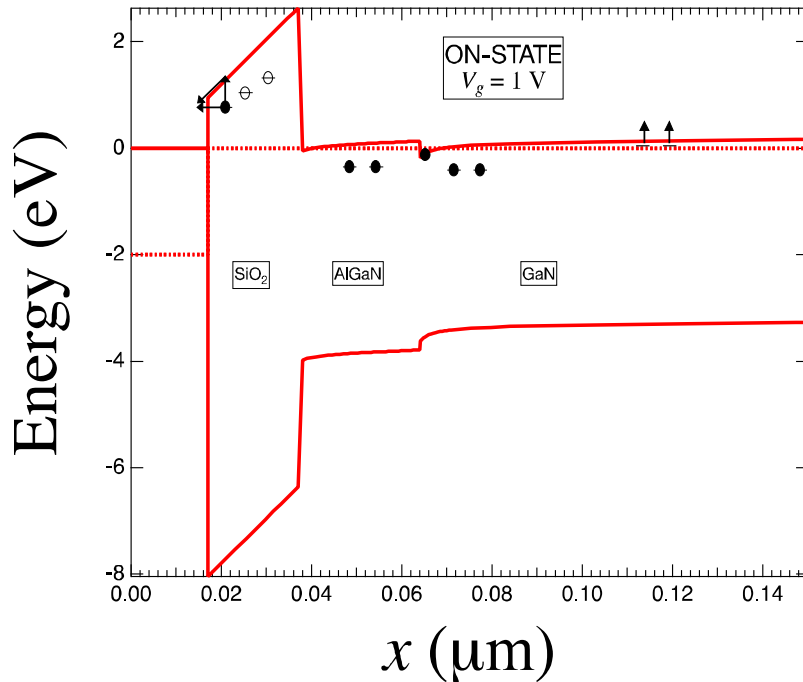
- Electron trapping leads to decreasing I_d
- Detrapping leads to increasing I_d
- Results suggest electron trapping at short recovery times (< 10 s) and emission for longer times
- Time constant spectrum reveals the presence of concurrent trapping and emission processes
- Temperature dependent peak present with $E_a = 0.58$ eV

Discussion – Off-State Stress



- Channel is depleted of carriers
- Electrons are injected into the SiO₂ from the gate
- Electron trapping in GaN buffer would result comparable parametric shifts
- Results in a positive ΔV_{th} and reduction in I_d

Discussion – Recovery Response



- Previously empty states at AlGaIn/GaN interface and in AlGaIn barrier are quickly filled
- Leads to initial current-collapse-like response
- Emission processes slowly begin to recover V_{th} and I_d

Conclusions

- Regularization techniques show improved resolution and robust reconstruction of complex recovery transient behavior of AlGaN/GaN HEMTs
- Time constant spectra show a temperature dependent peak consistent with 0.57 eV defect frequently observed in GaN
- Stress-time dependent peak is broad, shows little temperature sensitivity between 300 K and 330 K, and becomes progressively slower with increasing stress time
- MOS-HEMT devices show decreased ΔI_d compared to “Schottky”-gated devices and evidence of simultaneous trapping and detrapping processes during recovery